

# Seminar

---

---

## Institute for Plasma Research

---

---

**Title :** UV-VISIBLE Photodetection Properties of Pulsed Laser Deposited TiO<sub>2</sub> and Nb:TiO<sub>2</sub> Thin Films Grown on Si Substrate

**Speaker:** Dr. Avijit Dewasi  
Indian Institute of Technology, Roorkee

**Date :** 3rd August 2020 (Monday)

**Time :** 03:30 PM

**Venue :** Online - Join the talk:

[https://meet.ipr.res.in/Dr.AvijitDewasi\\_PDFTalk](https://meet.ipr.res.in/Dr.AvijitDewasi_PDFTalk)

### Abstract :

The UV-Visible photoresponse of anatase TiO<sub>2</sub> and Nb-doped TiO<sub>2</sub> (Nb:TiO<sub>2</sub>) thin film grown on *p*-type Si substrates (*p*-Si) will be presented systematically. TiO<sub>2</sub> thin film of different thicknesses (39-201 nm) were grown on pristine *p*-Si substrates to explore the influence of the TiO<sub>2</sub> film thickness on the antireflection, and photodetection properties of the *n*-TiO<sub>2</sub>/*p*-Si heterojunction structure. The photoresponsivity of the *n*-TiO<sub>2</sub>/*p*-Si heterostructure under ultraviolet (UV) and AM 1.5G solar simulated light was found to decrease with an increment of the thickness of the TiO<sub>2</sub> layer. TiO<sub>2</sub>(55 nm)/*p*-Si heterostructure exhibited the best photoresponse under the illumination of both UV and solar irradiance with responsivity ~0.14 A/W and ~0.09 A/W at -5V bias, respectively.

To improve the photoresponse of the optimized *n*-TiO<sub>2</sub> (55 nm)/*p*-Si heterojunction diode, TiO<sub>2</sub> layer (55 nm) was deposited on the chemically etched pyramidal textured *p*-Si substrate. After tuning the chemical etching parameters, the minimum total reflectance of ~7.6% was achieved for textured-Si substrate in the wavelength range of 300-900 nm. The reflectance further dropped down to 6.5% when the TiO<sub>2</sub> layer was deposited on the top surface of the textured Si substrate. TiO<sub>2</sub> (55 nm)/Textured-Si heterostructure exhibited a better response under the illumination of both UV and solar irradiance with responsivity ~0.22 A/W and ~0.13 A/W at -2V bias, respectively. One of the reasons for lower photoresponse was the high resistivity of TiO<sub>2</sub>. To improve the conductivity, Nb doping was introduced in the TiO<sub>2</sub> thin film and deposited on *p*-Si substrates. A comparative study on the UV-Visible light detection properties of the optimized Nb:TiO<sub>2</sub> thin films for two different concentrations of Nb doping (3.1 and 4.2 at.%) with the undoped TiO<sub>2</sub> was explored further. Under illuminated condition, *n*-Nb:TiO<sub>2</sub>/*p*-Si heterojunction with Nb doping concentration (4.2 at.%) in Nb:TiO<sub>2</sub> film showed better photoresponse with responsivity value (at -3V bias) 1.09 A/W and 1.60 A/W under solar simulated light and UV light, respectively. Moreover, the heterojunction photodiode exhibited fast photoresponse to both UV (rise time ~28 ms and fall time ~30 ms) and solar simulated light (rise time ~26 ms and fall time ~29 ms). The above findings enhanced our understanding about the fabrication of high-speed optoelectronic devices based on reverse-biased *n*-Nb:TiO<sub>2</sub>/*p*-Si heterojunctions.

---